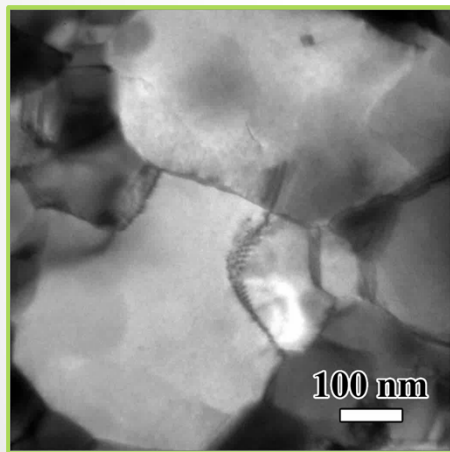




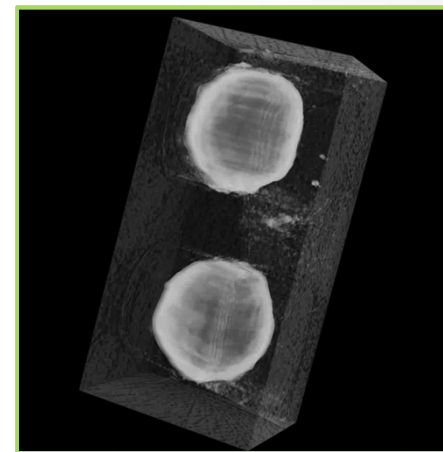
# Ion Beam Modification of Sliding Electrical Contacts and Nanomaterials



...

## Nanoscale Observations to Implementation

10 April, 2015



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# Motivation

- Sliding electrical contacts demand:
  - good conductivity
  - chemical stability
  - wear resistance
- Au meets the conductivity and chemical stability demands, but it lacks wear resistance.

## 1. Ion beams can modify electrical and mechanical properties.

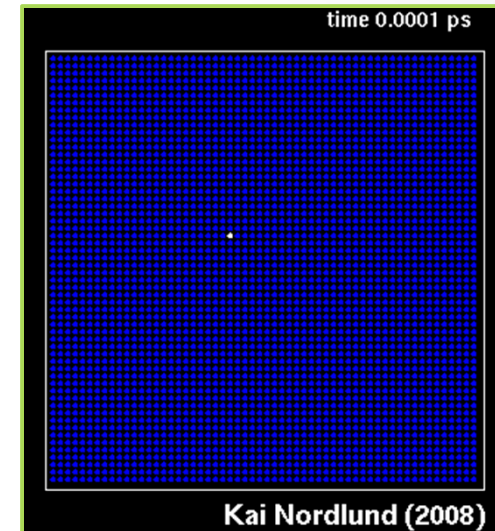
- Nanoparticle shape and size influences optical properties

## 2. Ion beams can modify nanoparticles on the nanoscale.



# Ion Beam Modification

- Energetic ion displaces one or more target atoms
  - Frenkel (vacancy-interstitial) pair
  - Collision cascade
  - Electronic interactions
- Ability to alter microstructure
  - Local reorganization of atoms
  - Defect production
  - Implanted species



*via Wikimedia Commons.*

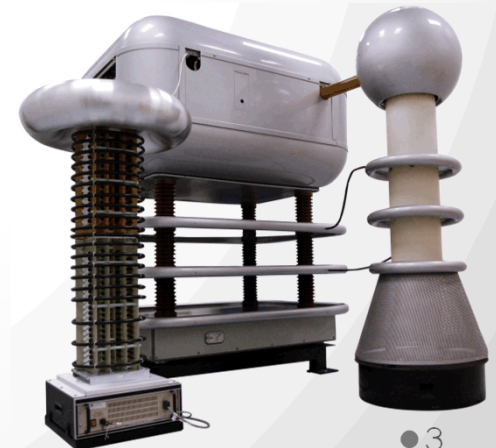
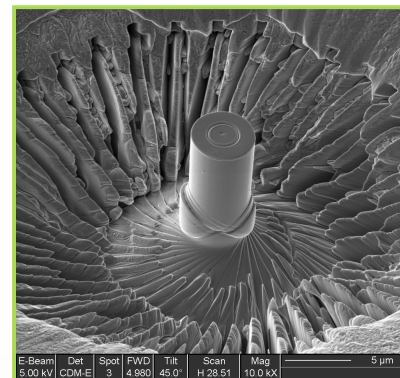
- **Interactions depend strongly on ion mass + energy and target atom mass + bonding.**

Averback, J Nucl Mater, 1994.

Ghaly & Averback, Phys Rev Lett, 1994.

Nordlund & Djurabekova, J Comput Electron, 2014.

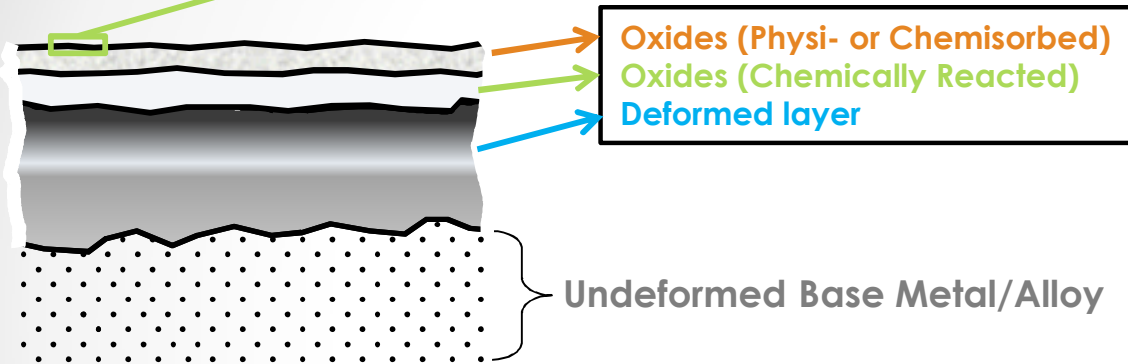
- Ions beams may be used for...
  - Semiconductor doping
  - Material removal (FIB milling)
  - Patterning/lithography
  - Analysis (mass spectrometry, ion microscopy)



# Nature of Metallic Surfaces



No surface is perfectly flat.

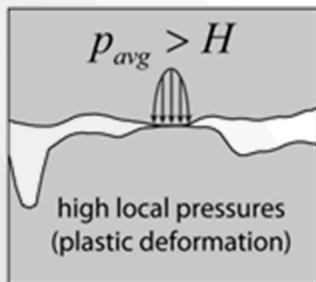


Real area of contact ( $A_r$ ) to be minimized for low adhesion (Low Adhesive Wear)...

...or maximized for low electrical contact resistance (ECR).

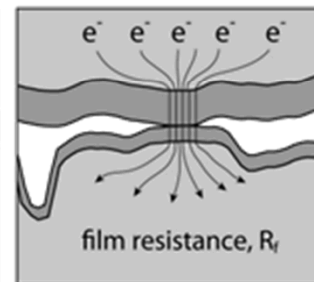
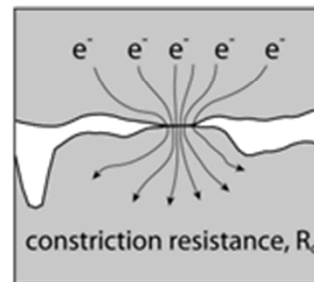
## Asperity Contacts, Constriction, Asperity Contacts and Surface Films

areal sum of asperity contacts and surface films define electrical contact resistance



... for metal contacts the real area is a function of hardness and contact force (Bowden & Tabor, 1939):

$$A_r \cong \frac{F_n}{H}$$



... ECR is a function of the constriction and film resistances:

$$ECR = \sum_i (R_{c,i} + R_{f,i})$$

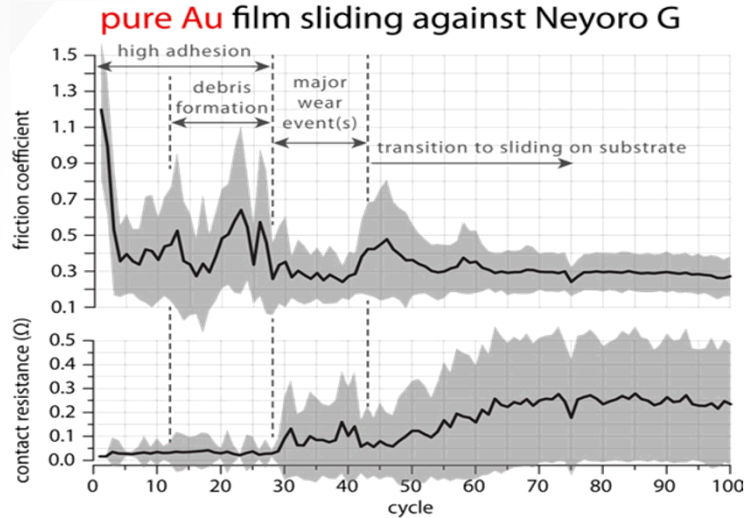
Archard, Journal of Applied Physics (1953) 24:981

R. Holm, Electrical Contacts Handbook (1958) Berlin: Springer-Verlag

Greenwood & Williamson, Proc. Royal Society (1966) A295:300

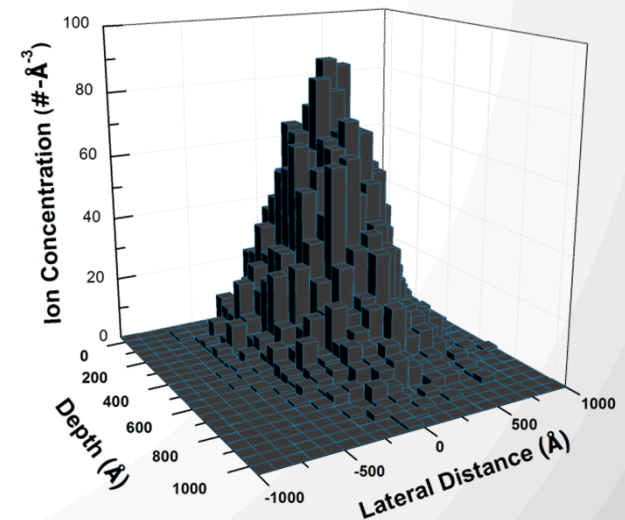
T.W. Scharf & S.V. Prasad, Journal of Material Science (2013) 48:511-531

# Experimental and Modeling Approaches



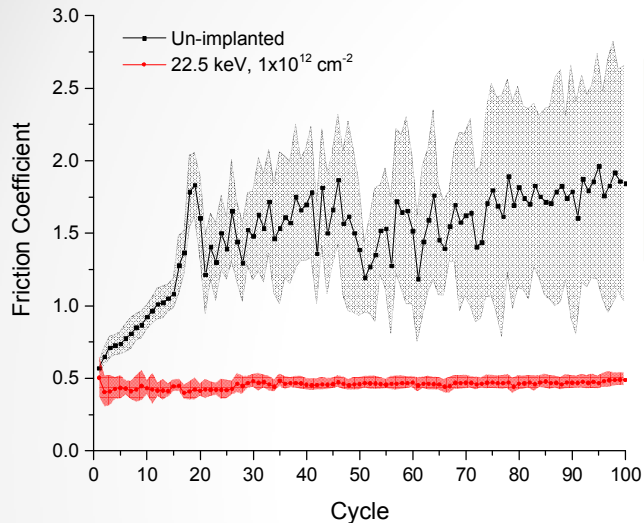
- **ECR-Tribology experiments** with Pure Au
- Neyoro G (Au-Cu), 1/16 in. radius hemispherical tip rider
- $F_n = 100$  mN ( $\approx 290$  MPa contact stress)
- 100 Cycles @  $v = 1$  mm/s
- 1 – 2 mV bias to achieve approximately 100 mA
- Lab air environment at room temperature

- **Simulations:** SRIM 2008 (The Stopping and Range of Ions in Matter, J.F. Ziegler, M.D. Ziegler and J.P. Biersack)
  - Monte-Carlo simulation of kinematic interaction based on empirical data fitted functions
  - Input variables of target material include density, AMU, and thickness.
  - Input variables of ions include AMU, energy, and angle of incidence.
  - Assumes isotropic material, thus no consideration for channeling effects

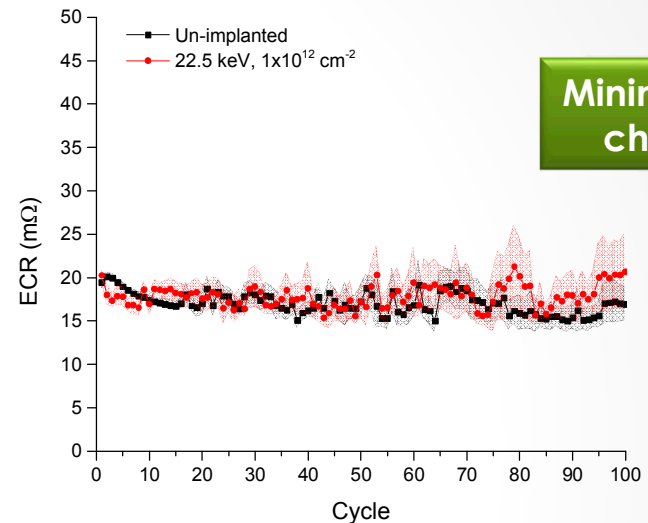


# ECR and Wear Measurements

Au implanted @ 22.5 keV to  $1 \times 10^{12} \text{ cm}^{-2}$



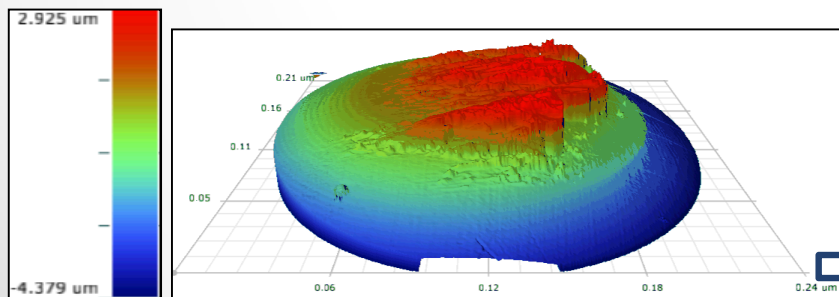
Factor of ~3  
Improvement  
in friction  
coefficient.



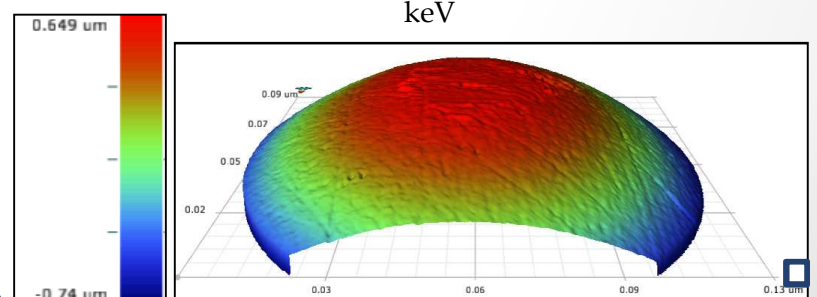
Minimal ECR  
change

Friction significantly reduced with  $^3\text{He}$  implantation while maintaining ECR performance.  
Scanning white light interferometer topographical construction of riders after 100 cycles:

Rider after 100 cycles against Un-implanted Au



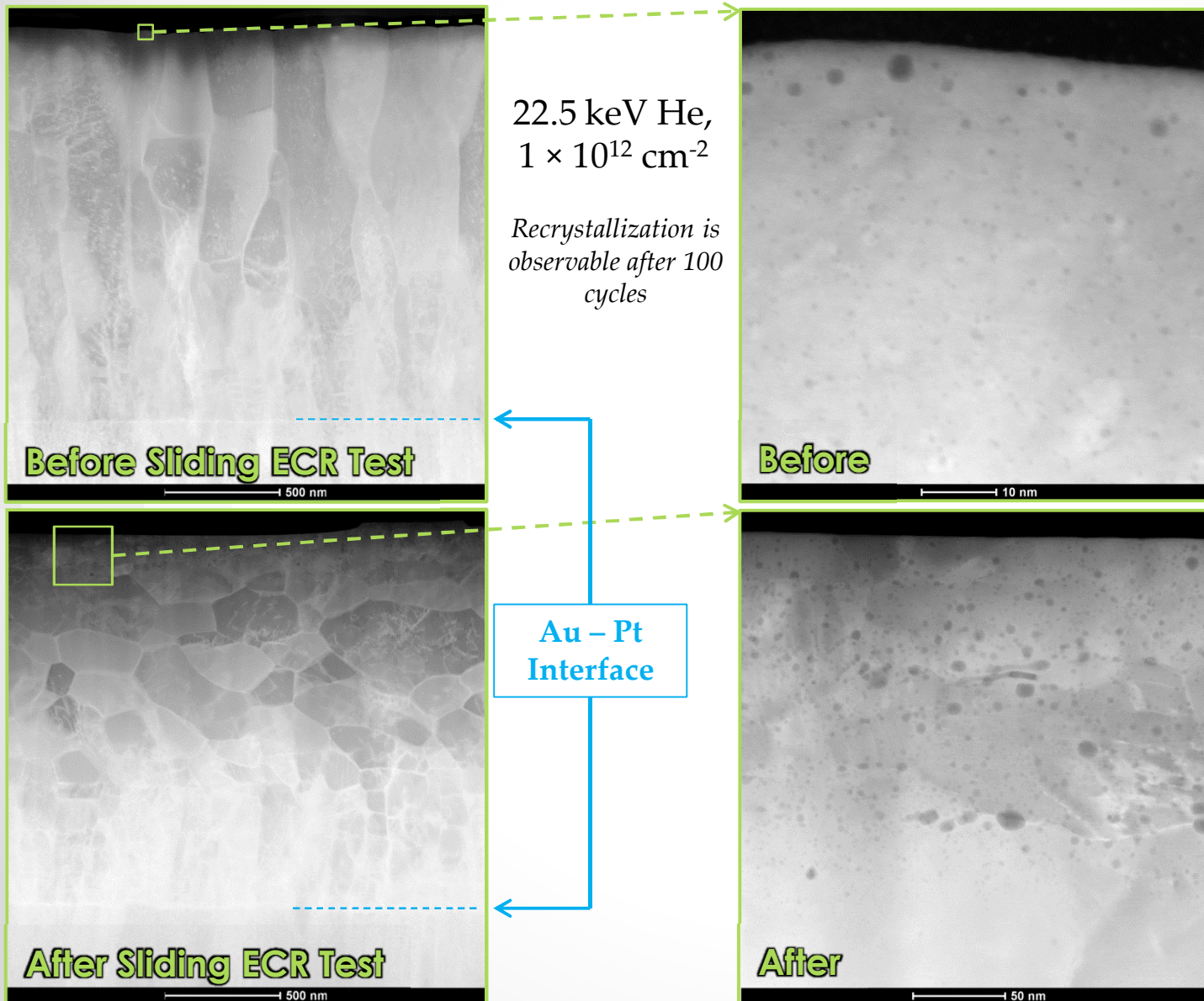
Rider after 100 Cycles against Au implanted to  $1\text{E}12 \text{ cm}^{-2}$  @ 22.5 keV





# STEM Images of Sub-surfaces

Collaborators: P. Kotula



He implantation  
results in small  
dispersed spherical  
structures assumed  
to be He bubbles.  
Dispersion and depth  
can be tailored

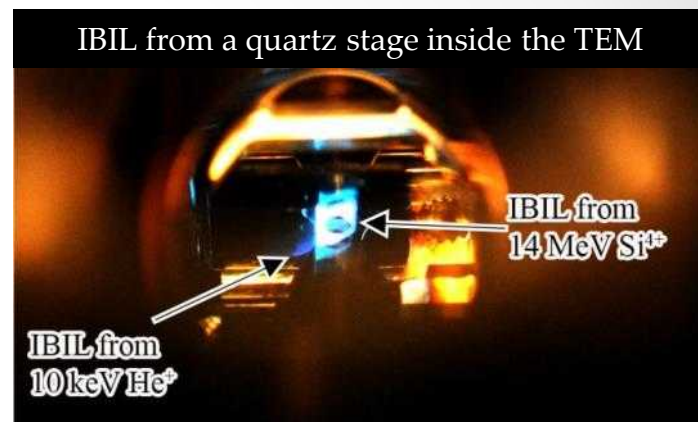
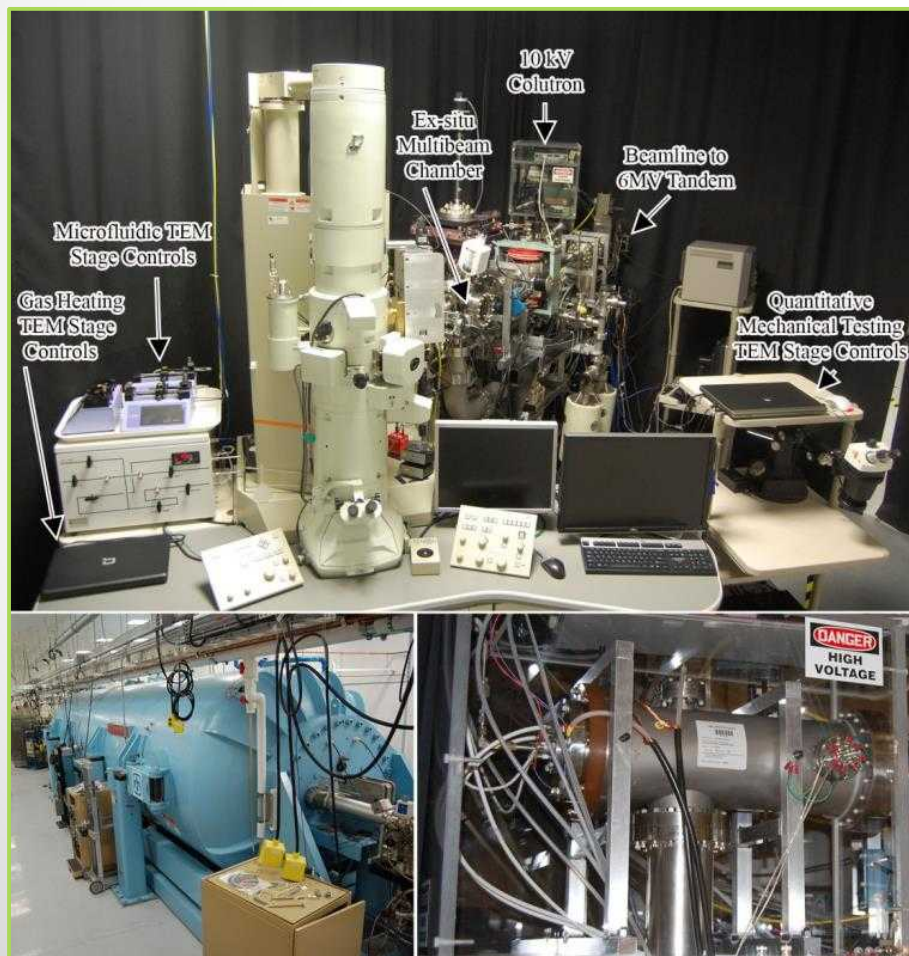
An increase in both  
observable density and  
diameter of He  
bubbles, suggests  
wear induced He  
coalescence from  
interstitial and  
previously  
unobservable He

# Sandia's Concurrent *In situ* Ion Irradiation TEM



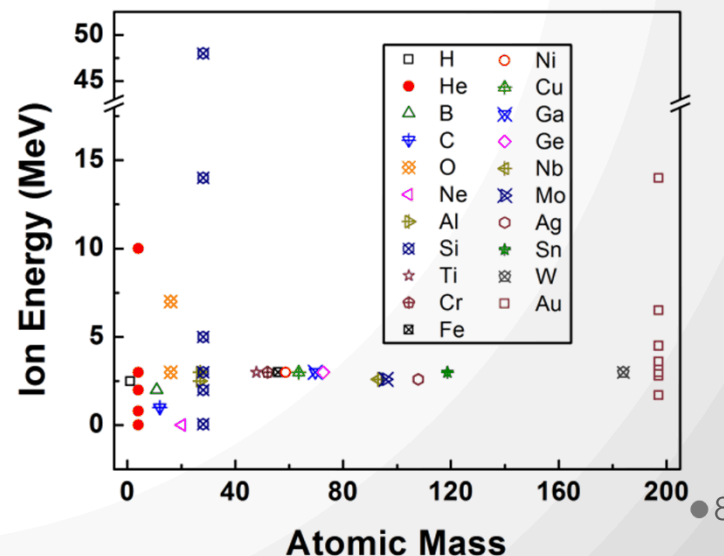
Collaborator: D.L. Buller

10 kV Colutron - 200 kV TEM - 6 MV Tandem



Direct real time observation of ion irradiation, ion implantation, or both with nanometer resolution.

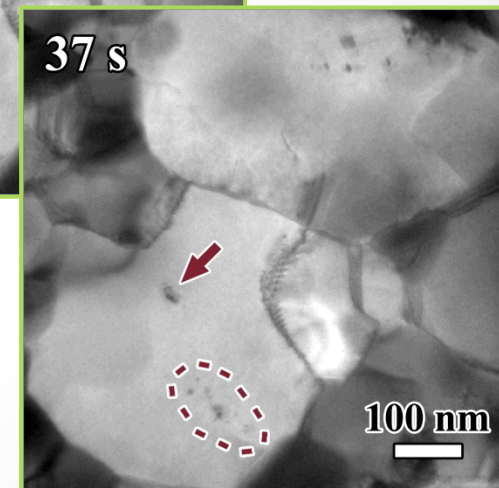
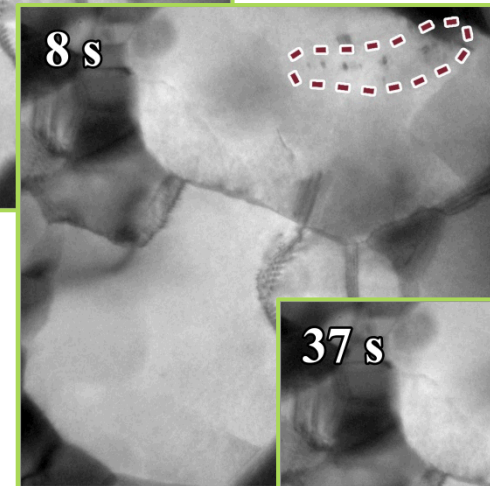
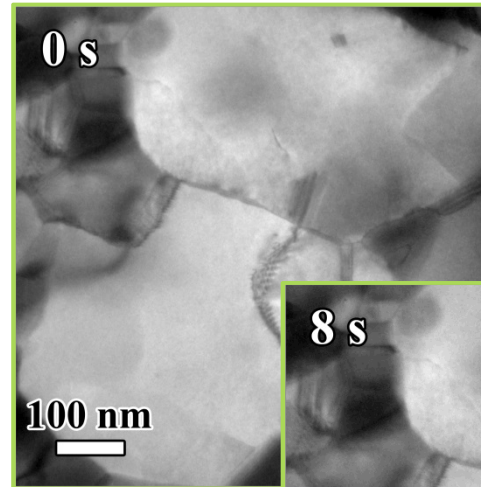
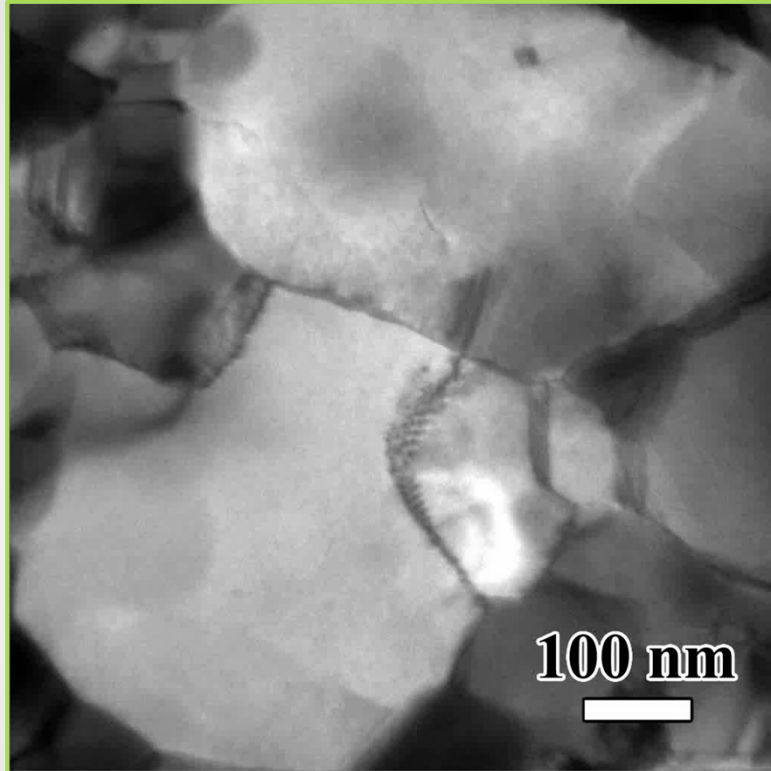
Ion species & energy introduced into the TEM





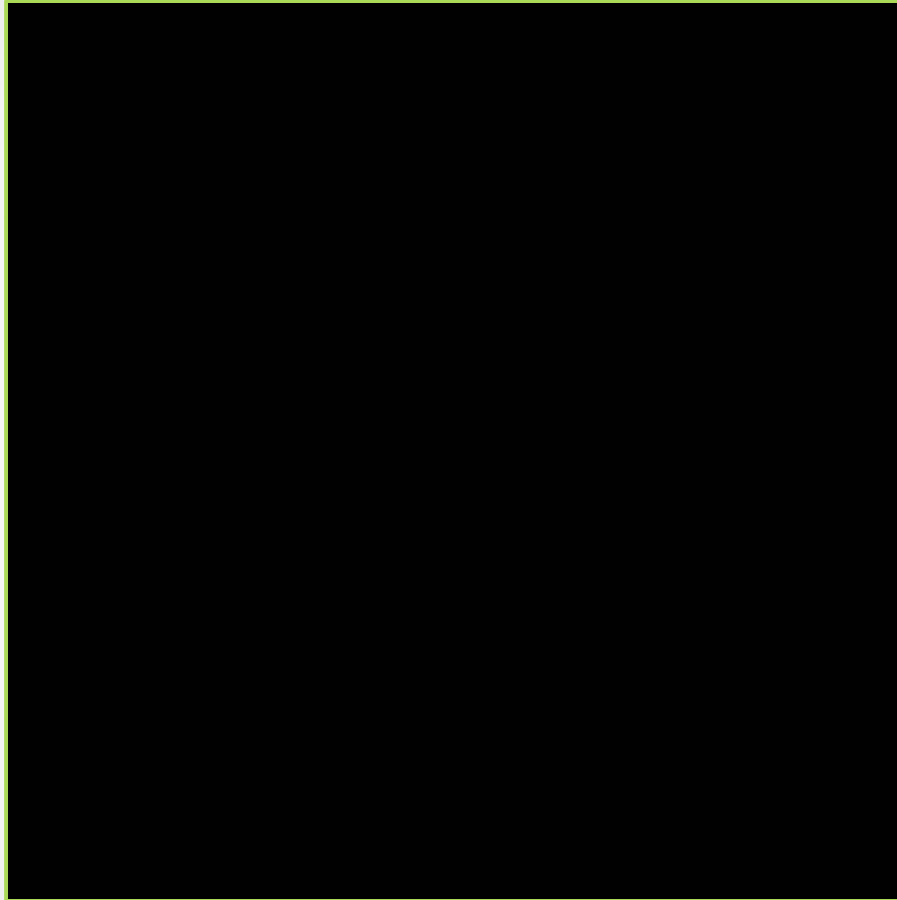
# TEM: 3.6 MeV Au<sup>6+</sup>

Video playback speed ×5.



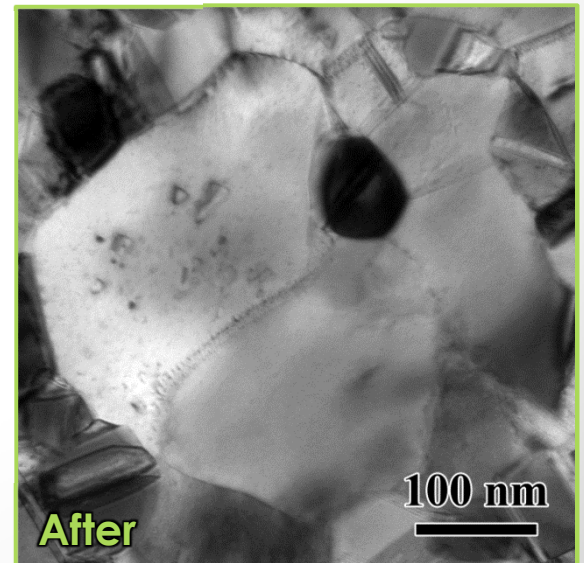
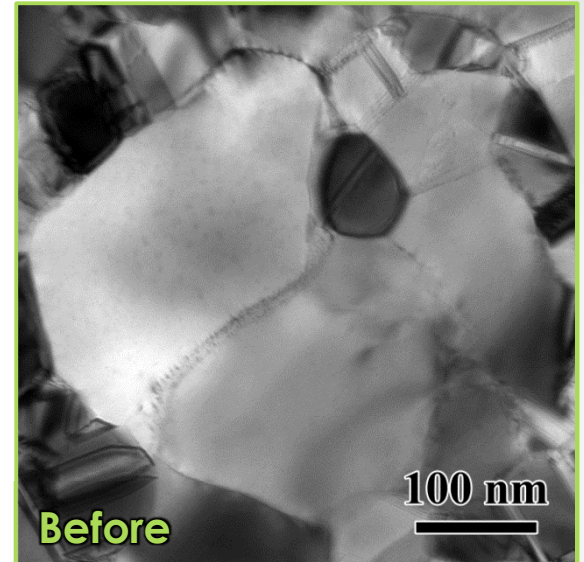
- 3.6 MeV Au<sup>6+</sup> ions at  $2.1 \times 10^8$  ions cm<sup>-2</sup> s<sup>-1</sup>
- Large defect clusters from cascades
- **Degradation of wear properties**

# TEM: 10 keV He<sup>+</sup>



- 10 keV He<sup>+</sup> ions at  $2.9 \times 10^{13}$  ions cm<sup>-2</sup> s<sup>-1</sup>
- Gradual formation and growth of dislocation loops

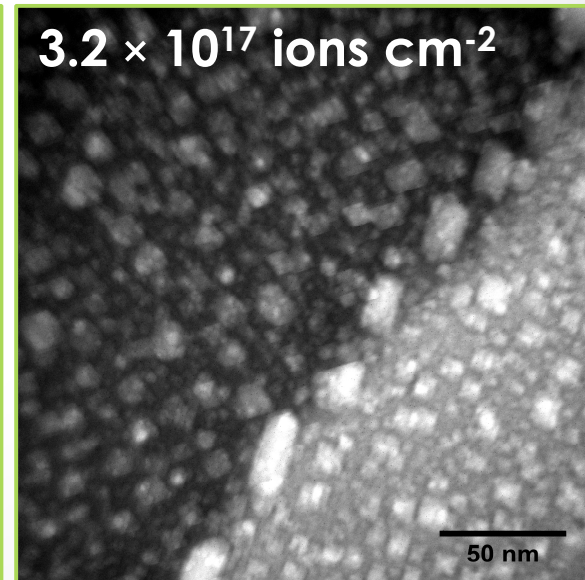
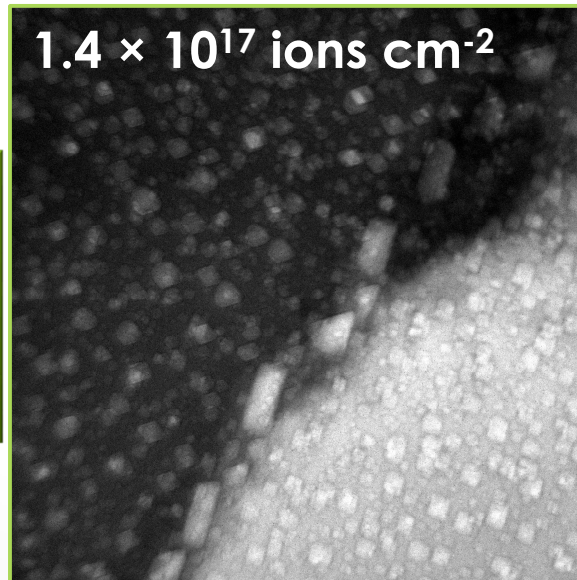
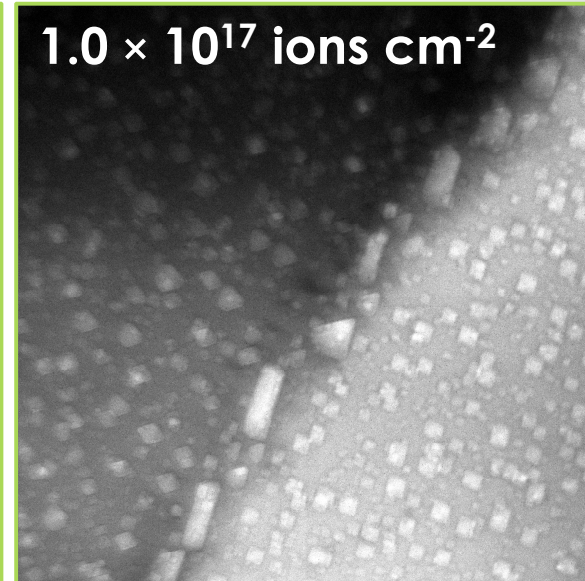
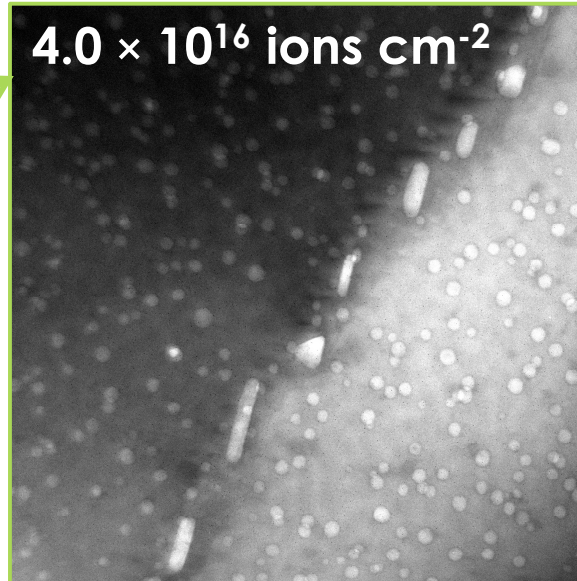
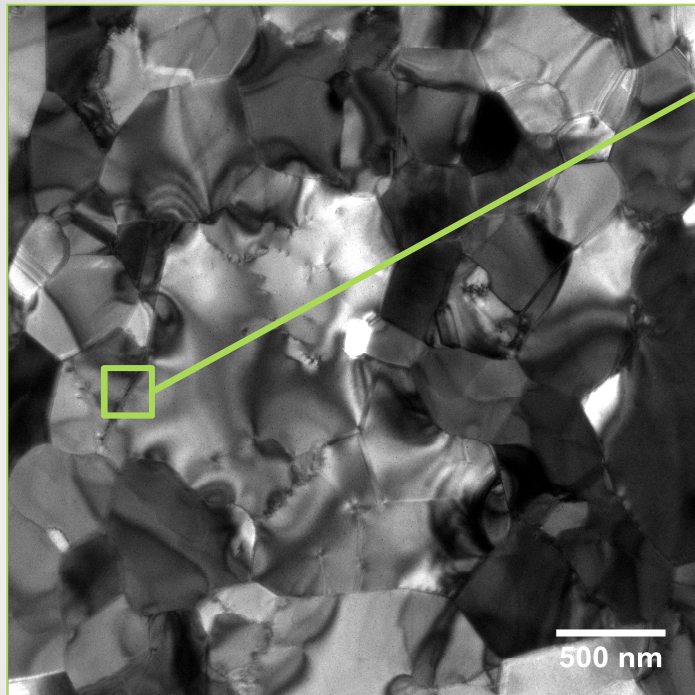
● TMS 2015





# Extremes of *In Situ* Implantation

Collaborators: C. Chisholm, P. Hosemann, & A. Minor

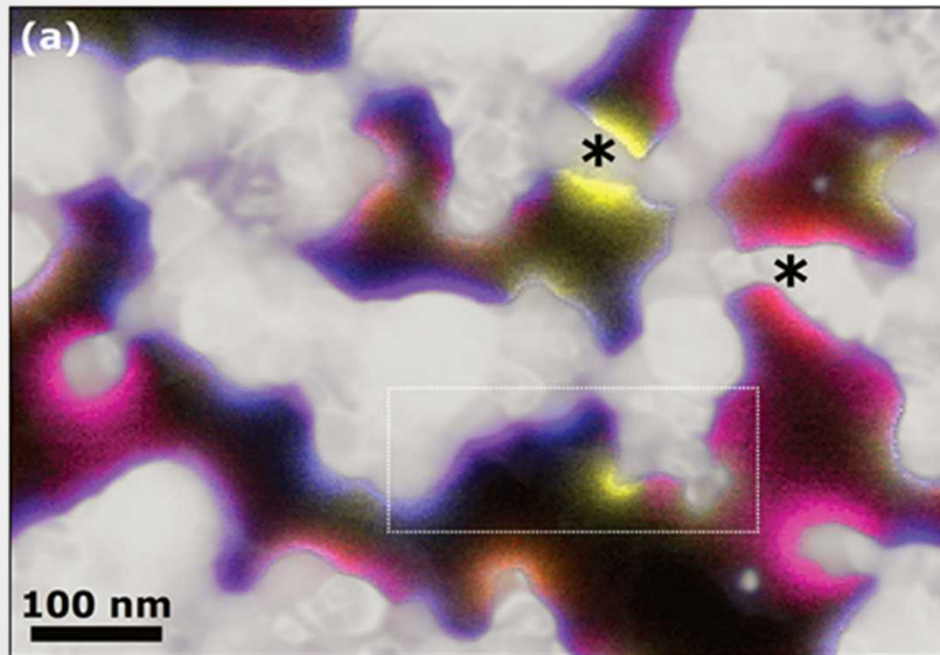




**10 keV He<sup>+</sup> into Au TEM foil**

**Result: Faceted cavities form  
a porous microstructure.**

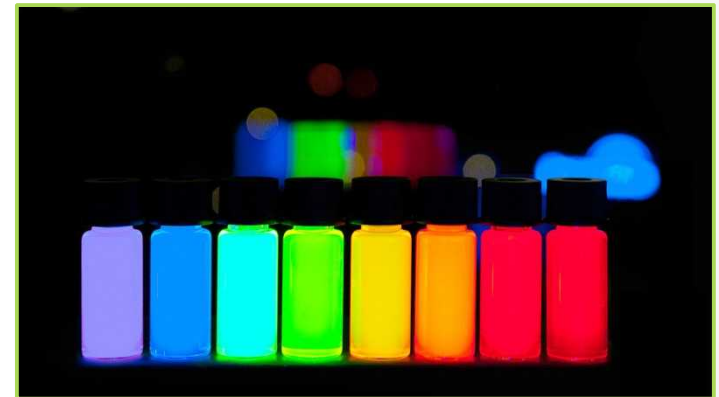
# Optical properties

Optical properties of nanostructured materials depend sensitively on size and shape.



Wavelength (nm)	1080	730	575	430	360
					
Energy (eV)	1.15	1.70	2.15	2.90	3.45

Bosman, *et al*, Nanotech, 2007.



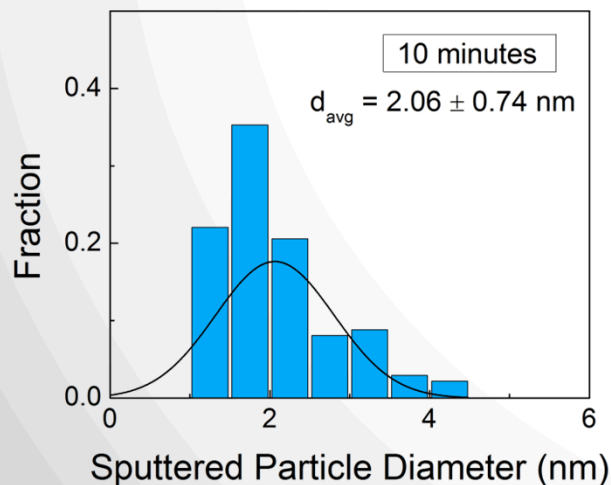
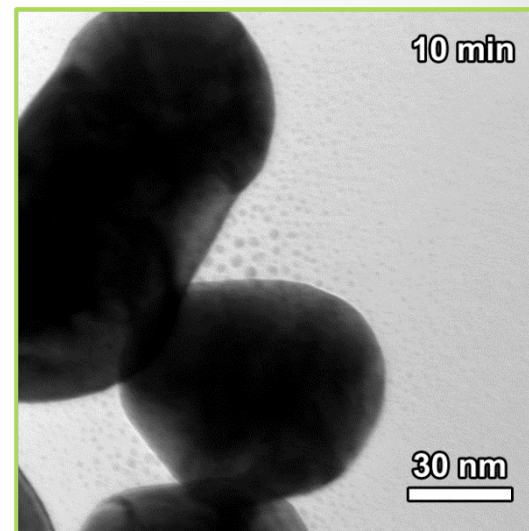
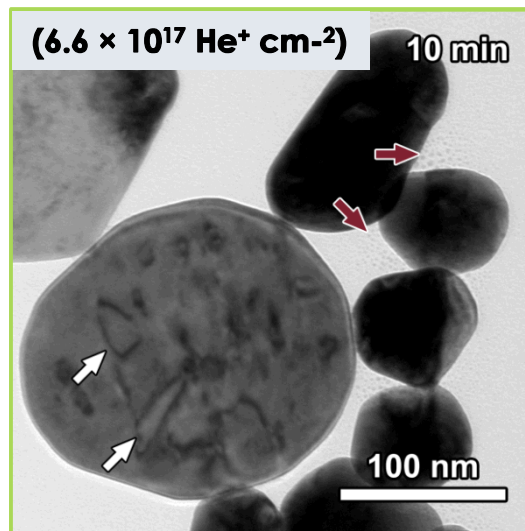
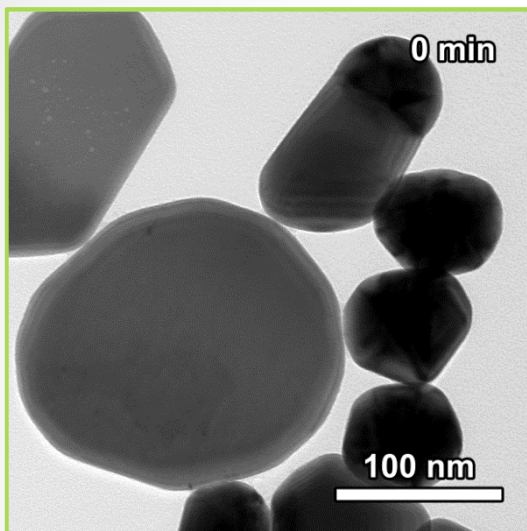
Antipoff, 2012, *via* Wikimedia Commons.

**Ion beams can modify these materials in ways not possible by other means.**

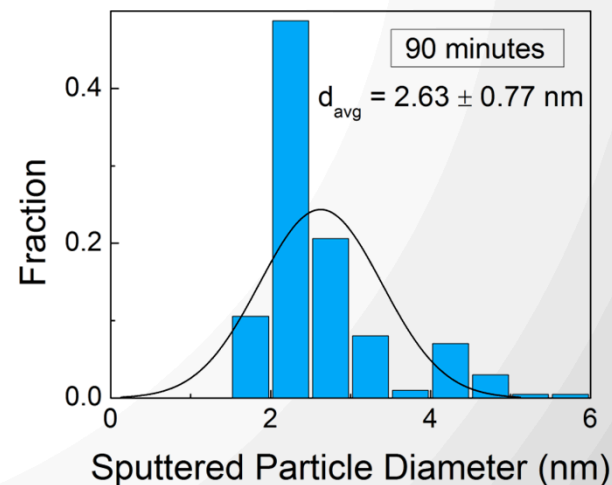
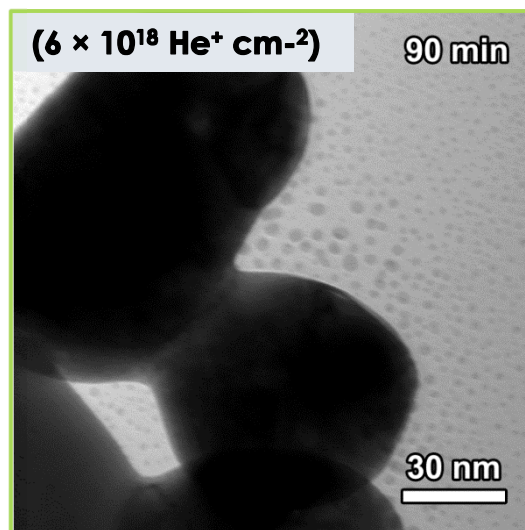


# Structural Modification of Nanoparticles by He implantation

Collaborators: S.H. Pratt & T.J. Boyle



● TMS 2015

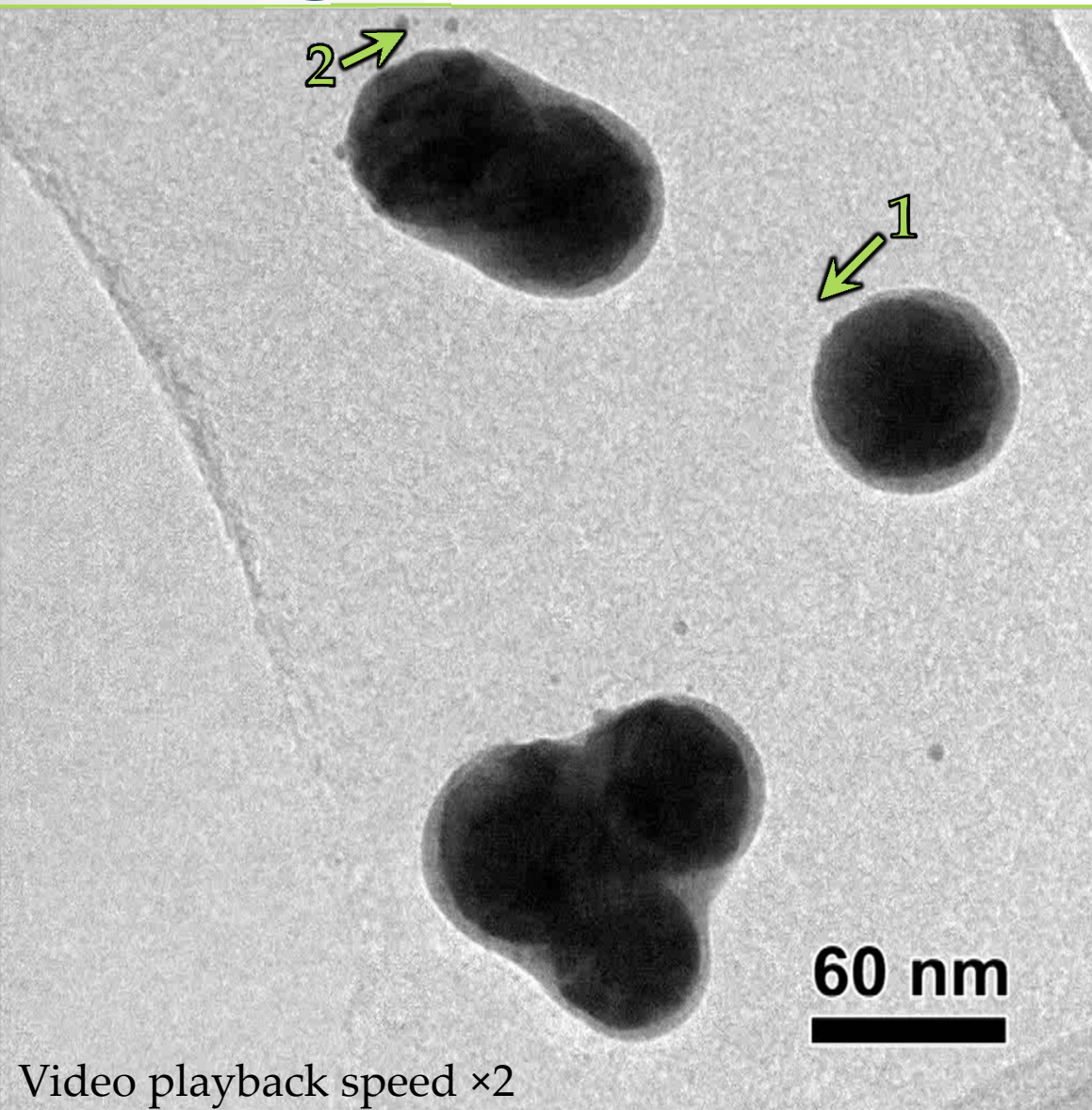


● 13

# Single Ion Strikes

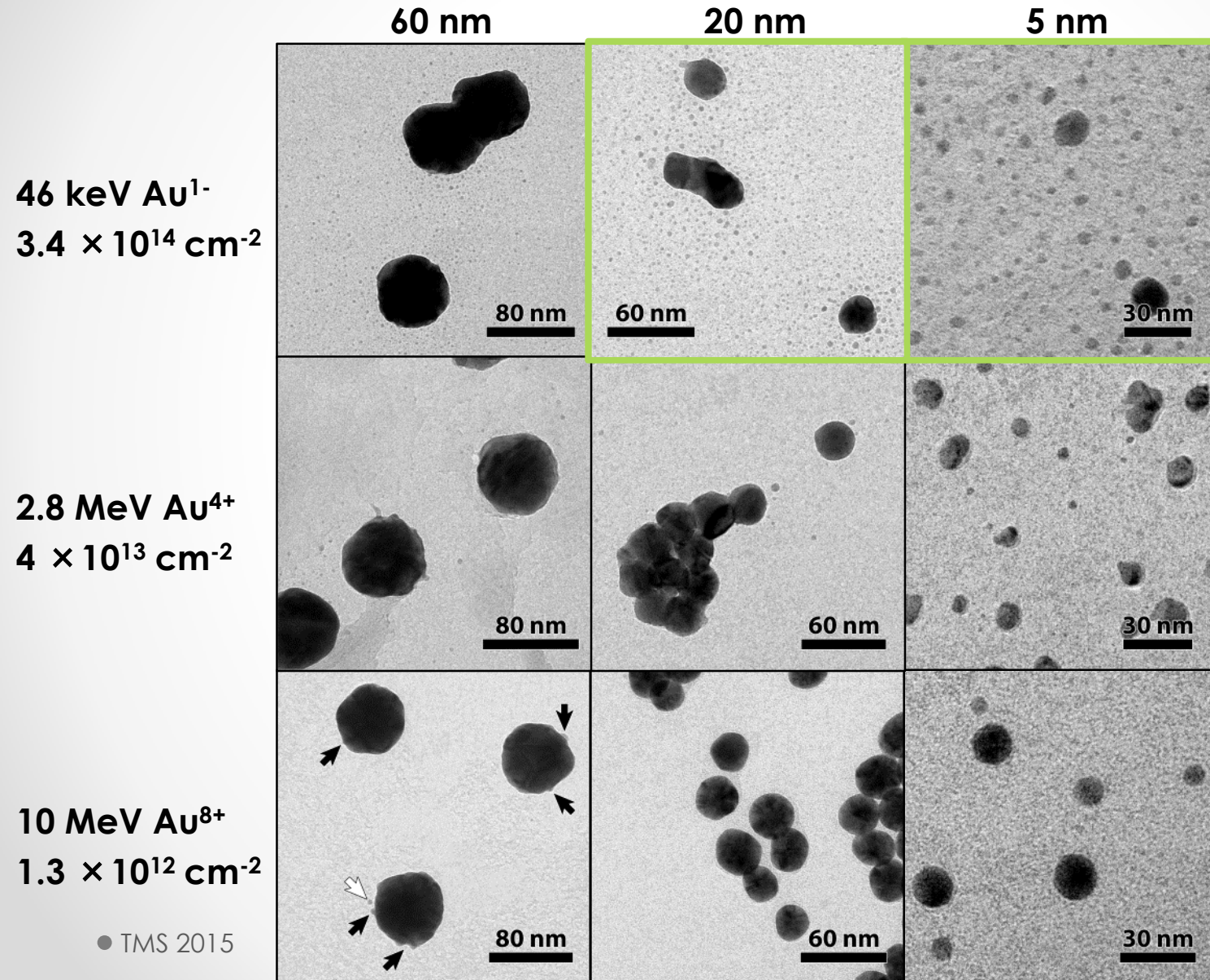
- 2.8 MeV Au<sup>4+</sup> ions into 60 nm diameter Au nanoparticles
- 100 kx magnification
- Nanoscale filaments created by individual ions
  - Filaments evolve over time

**The permanent and transient structures resulting from single ion strikes can be directly observed.**





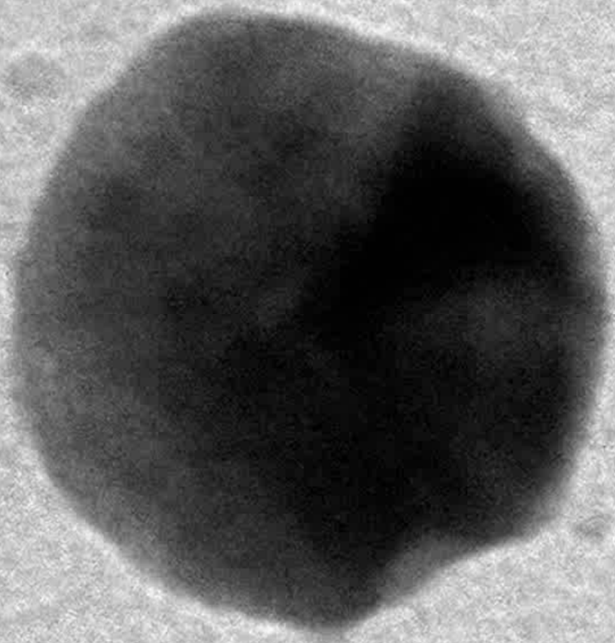
# Varying Ion Energy and Au Particle Size



Particle size and ion energy dictate the ratio of sputtering, particle motion, particle agglomeration, and other active mechanisms.

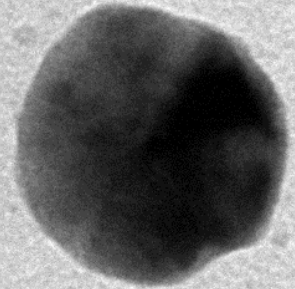
# Single Ion Effects: 20 nm

46 keV Au<sup>1+</sup> ions



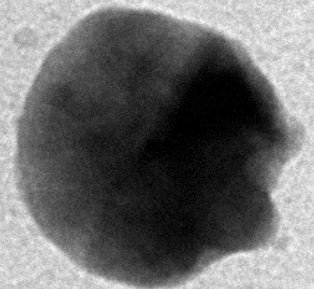
10 nm

t = 0 s



10 nm

t = 0.25 s





# Single Ion Effects: 5 nm

46 keV Au<sup>1+</sup> ions

10 nm  

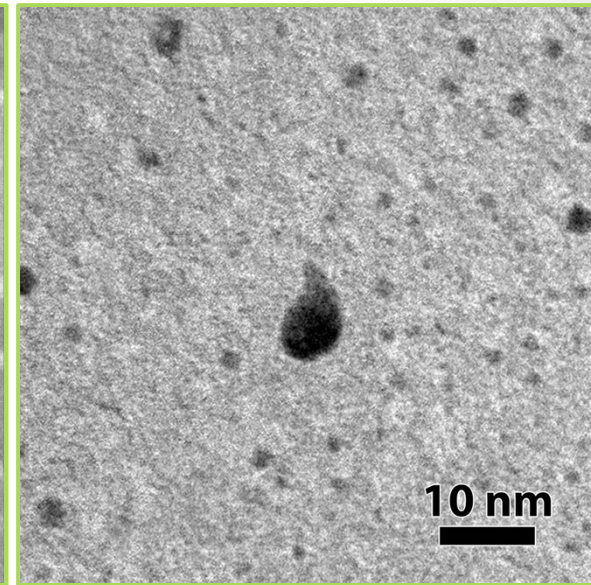
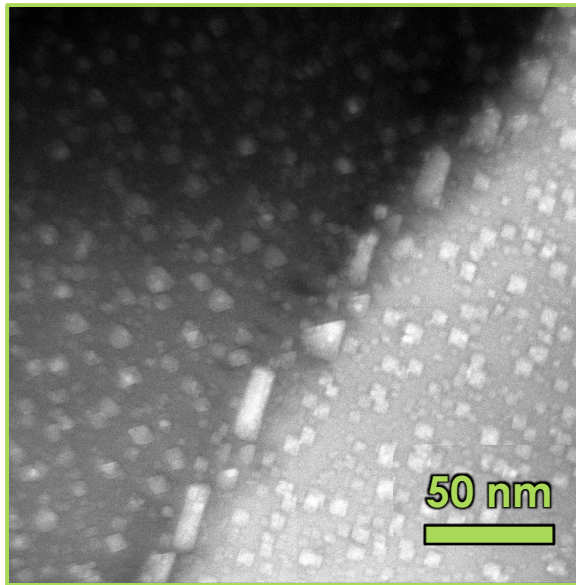
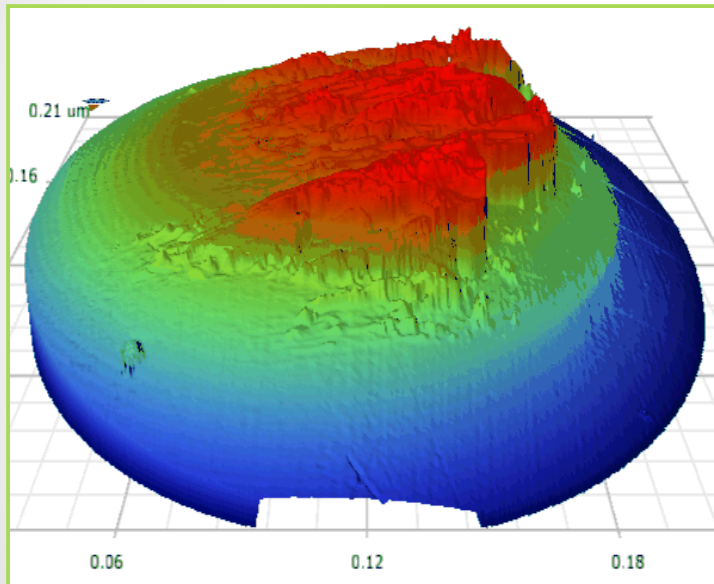

t = 0 s

10 nm  




# Summary and Conclusions

- Demonstrated improvement in Au sliding contacts via He implantation
- Ion beams may also be used to change shape and size of nanoparticles



- Acknowledgements: Prof. T.W. Scharf (UNT), P. Hosemann (UC Berkeley), C. Chisholm & A. Minor (UC Berkeley and LBNL), T.J. Boyle, D.L Buller, P. Kotula, S.H. Pratt. This work was partially supported by the Division of Materials Science and Engineering, Office of Basic Energy Sciences, U.S. Department of Energy.